



## Science and Technology of Materials, Interfaces, and Processing

### Topical Areas

Biomaterials  
Environmental S&T  
Magnetic Materials  
Manufacturing S&T  
Materials Characterization  
Materials Processing  
MEMS  
Microelectronic Materials  
Nanometer-Scale S&T  
Plasma S&T  
Surface Engineering  
Surface Science  
Thin Films  
Vacuum Technology

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### AVS Announces its 64th International Symposium and Exhibition on October 29-November 3, 2017, in Tampa, Florida

#### Featuring Technical Symposia, Focused Topics, Short Courses, Exhibitor Technology Spotlights, and an Equipment Exhibition

New York, February 14, 2017—The AVS 64<sup>th</sup> International Symposium and Exhibition will be held October 29-November 3, 2017, at the Tampa Convention Center, in Tampa, Florida. Highlights include an extensive collection of technical sessions, exhibitor technology spotlights, short courses, and a free to attend equipment exhibition. Starting in February, abstracts of original work will be accepted at [www.avs.org](http://www.avs.org) through May 1, 2017.

This year's annual meeting theme is intended to investigate, understand and provide solutions to the challenges for Next Generation technologies. A sampling of topics that encompass this theme will include:

- 2D Materials
- Actinides and Rare Earths
- Advanced Ion Microscopy
- Advanced Surface Engineering
- Applied Surface Science
- Biomaterial Interfaces and Biomaterials Plenary
- Electronic Materials and Photonics
- Exhibitor Technology Spotlight
- Fundamental Discoveries in Heterogeneous Catalysis
- Magnetic Interfaces and Nanostructures
- Manufacturing Science and Technology
- MEMS and NEMS
- Nanometer-scale Science and Technology
- Novel Trends in Synchrotron and FEL-Based Analysis
- Plasma Processing for Biomedical Applications
- Plasma Science and Technology
- Scanning Probe Microscopy
- Spectroscopic Ellipsometry
- Surface Science
- Sustainability
- Tandem MS
- Thin Films
- Tribology
- Vacuum Technology

This year's plenary speaker is Paul S. Weiss, UC Presidential Chair, Distinguished Professor of Chemistry and Biochemistry, Distinguished Professor of Materials Science & Engineering, California NanoSystems Institute, University of California, Los Angeles.

For more information, please access the AVS Website at [www.avs.org](http://www.avs.org) or contact the AVS at 212-248-0200, fax: 212-248-0245, e-mail: [avsnyc@avs.org](mailto:avsnyc@avs.org).

AVS 64 Complimentary Press Badge Form: <https://www.avs.org/About/Press-Media-Center>.

*As a professional membership organization, AVS fosters networking within the material, processing, and interfaces community at the local, national, and international meeting and exhibits throughout the year. AVS annually publishes four journals, honors and recognizes members through its prestigious awards program, offers training and other technical resources, as well as career services.*

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